

AMENDMENT TRANSMITTAL LETTER

Docket Number
GOM-02001

Application Number
09/818,972

Filing Date
March 27, 2001

Examiner
Anna Crowell

Group Art Unit
1762

Invention Title

METHOD OF FORMING SILICON OXIDE FILM AND FORMING APPARATUS THEREOF

TO THE COMMISSIONER FOR PATENTS

Transmitted herewith is an amendment in the above-identified application, including:

- (X) Amendment and Response;
- (X) Postcard Receipt

CLAIMS AS AMENDED

(1)		(2)	(3)			
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NUMBER PREVIOUSLY PAID FOR	PRESENT NUMBER EXTRA	RATE	FEE
TOTAL CLAIMS	14	minus	20	0	x \$18	\$0
INDEPENDENT CLAIMS	3	minus	3	0	x \$86	\$0
MULTIPLE DEPENDENT CLAIM ADDED					\$290	
					TOTAL	\$0
If applicant has small entity status under 37 CFR 1.9 and 1.27, then divide total fee by 2, and enter amount here.			SMALL ENTITY TOTAL		\$	

* If the entry in column 1 is less than the entry in column 2, write "0" in column 3.
 ** If the highest number previously paid for IN THIS SPACE is less than 20, enter "20."
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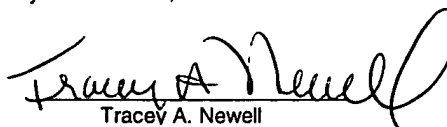
- () Please charge **Deposit Account Number 03-1721** in the amount of \$_____. A duplicate copy of this sheet is enclosed.
- () A check in the amount of \$_____ to cover the filing fee,
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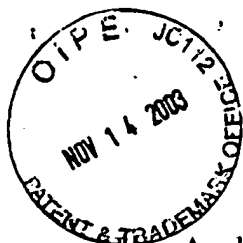


Donald W. Muirhead, Reg. No. 33,978

November 12, 2003
Date

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on this 12th day of November, 2003.


Tracey A. Newell



1762

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Katsuhisa YUDA, et al.

Appl. No.: 09/818,972

Art Unit: 1762

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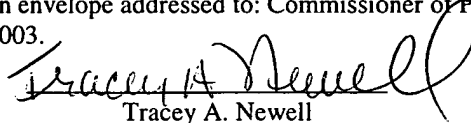
For: METHOD OF FORMING SILICON
OXIDE FILM AND FORMING
APPARATUS THEREOF

Atty Docket: GOM-02001

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Tracey A. Newell

AMENDMENT AND RESPONSE TO OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This paper is being provided in response to the Office Action dated August 14, 2003 for the above-captioned U.S. patent application.

Amendments to the Claims are reflected in the listing of claims that begins on page 2 of this paper.

Remarks begin on page 7 of this paper.

It is not believed that extensions of time or fees for net addition of claims are required, beyond those which may otherwise be provided for in documents accompanying this paper. However, in the event that additional extensions of time are necessary, then such extensions of time are hereby petitioned under 37 C.F.R. § 1.136(a), and any fees required for consideration of this paper (including fees for net addition of claims) are authorized to be charged in two originally-executed copies of an Amendment Transmittal Letter filed herewith.